

IN THE CLAIMS:

Please cancel, amend, retain or add the claims as set forth herein.

1. (Currently Amended) A semiconductor factory automation (FA) system, comprising:
at least one processor, which is coupled to at least one semiconductor processing means for processing a semiconductor wafer cassette containing a predetermined number of semiconductor wafers, for driving a program process and providing processor state information, wherein the processor state information includes an availability of a central processing unit related to said processor, an availability of a disk related to said processor, and a state of the program process related to said processor;

[[a]] storing means for storing the processor state information in [[a]] real time;

[[a]] monitoring means for retrieving the processor state information in said storing means to monitor said processor; and

[[a]] displaying means for displaying the processor state information retrieved.

2. (Original) The semiconductor FA system as recited in claim 1, wherein said displaying means includes:

a first display space for displaying the availability of the central processing unit related to said processor; and

a second display space for displaying the availability of the disk related to said processor.

3. (Currently Amended) The semiconductor FA system as recited in claim 2, wherein said displaying means further includes:

a first light emitting device for emitting a first light when the disk has failed;

a second light emitting device for emitting ~~the~~ a second light when the program process is in a down state; and

A1 a third light emitting device for emitting ~~the~~ a third light when a communication between said monitoring means and said processor is disconnected. /

4. (Original) The semiconductor FA system as recited in claim 3, wherein said displaying means further includes:

a third display space for displaying identification information of the program process of the down state.

5. (Canceled).

6. (Currently Amended) The semiconductor FA system as recited in claim ~~[[5]]~~ 4, wherein said at least one processor includes a first processor and a second processor.

7. (Currently Amended) The semiconductor FA system as recited in claim ~~[[6]]~~ 4, further comprising:

~~a semiconductor processing means coupled to said first processor for processing a semiconductor wafer cassette containing a predetermined number of semiconductor wafers;~~

~~[[a]] stocking means coupled to said second processor for stocking the semiconductor wafer cassette; and~~

~~[[a]] transportation means for transporting the semiconductor wafer cassette from said semiconductor processing means to said stocking means or from said stocking means to said semiconductor processing means.~~

AM 8. (Currently Amended) A method for monitoring at least one server in a semiconductor factory automation (FA) system, comprising the steps of:

a) providing server state information from at least one server, which is coupled to at least one semiconductor processing means, to a real-time database, wherein the server state information includes an availability of a central processing unit related to the server, an availability of a disk related to the server, and a state of a program process related to the server;

b) storing the server state information in the real-time database;

c) retrieving the server state information to monitor the server; and

d) displaying the server state information retrieved.

9. (Original) The method as recited in claim 8, wherein said step d) includes the steps of:

d1) displaying the availability of the central processing unit related to the server; and

d2) displaying the availability of the disk related to the server.

10. (Currently Amended) The method as recited in claim 9, wherein said step d) further includes the steps of:

d3) emitting a first light when the disk has failed; and

d4) emitting ~~the~~ a second light when the program process is in a down state.

11. (Original) The method as recited in claim 10, wherein said step d) further includes the step of:

d5) displaying identification information of the program process of the down state.

12. (New) A semiconductor factory automation (FA) system, comprising:

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a plurality of processors, each coupled to a plurality of semiconductor processing means for processing a semiconductor wafer cassette containing a predetermined number of semiconductor wafers, said plurality of processors for driving a plurality of program processes, respectively, and providing respective processor state information, wherein for each of said plurality of processors the processor state information respectively includes an availability of a central processing unit related to said processor, an availability of a disk related to said processor, and a state of the program process related to said processor;

storing means for storing the processor state information of said plurality of processors in real time;

monitoring means for retrieving the processor state information in said storing means to monitor said plurality of processors; and

displaying means for displaying the processor state information retrieved, said displaying means including, for each processor,

- a first display space for displaying the availability of the central processing unit related to said processor; and
- a second display space for displaying the availability of the disk related to said processor.

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13. (New) The semiconductor FA system as recited in claim 12, wherein said displaying means further includes, for each processor:

- a first light emitting device for emitting a first light when the respective disk has failed;
- a second light emitting device for emitting a second light when the respective program process is in a down state; and
- a third light emitting device for emitting a third light when a communication between said monitoring means and said respective processor is disconnected.

14. (New) The semiconductor FA system as recited in claim 13, wherein said displaying means further includes, for each processor:

- a third display space for displaying identification information of the program process of the down state.